

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
Hiroshi TOYODA, et al.)	Group Art Unit: 2814
Application No.: 10/600,568)	Examiner: Weiss, Howard
Filed:	June 23, 2003)	
For:	METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE INCLUDING TWO-STEP POLISHING OPERATION FOR CAP METAL (As Amended Herein)))))	
Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450			
Sir:			

AMENDMENT

In reply to the Office Action of January 12, 2004, with a period for response extending through April 12, 2004, please amend the application as follows. Applicants also respectfully request the Examiner's reconsideration in view of the remarks that follow:

An Amendment to the Title is shown on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims beginning on page 3 of this paper.

Remarks begin on page 7 of this paper.

Application Number: 10/600,568

Filing Date: June 23, 2003 Attorney Docket Number: 04329.2444-01

AMENDMENT TO THE TITLE:

Please amend the title of the application as follows. On page 1, please replace the title at lines 2 and 3 with the following title:

--METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE <u>INCLUDING</u>

<u>TWO-STEP POLISHING OPERATION FOR CAP METAL</u> AND <u>SEMICONDUCTOR</u>

<u>DEVICE</u>--